

Lecture 8

NEMS and Piezoelectric Transistor

ELEN 6907, Columbia University
Emerging Nanoelectronic Devices

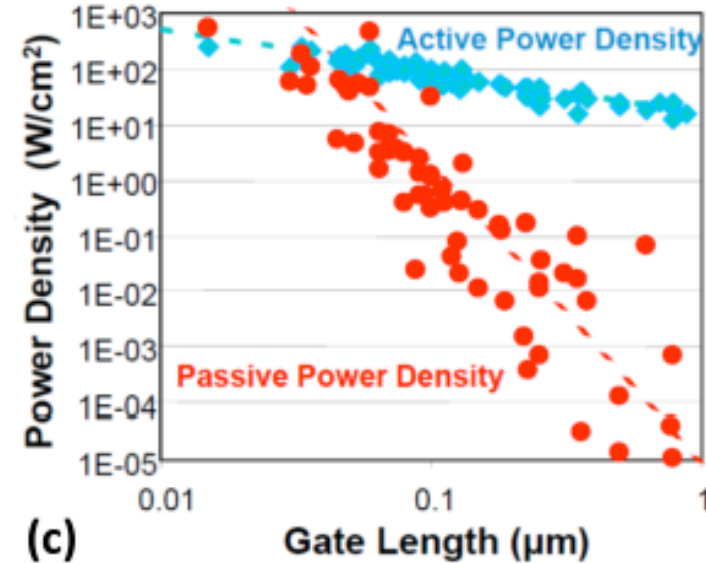
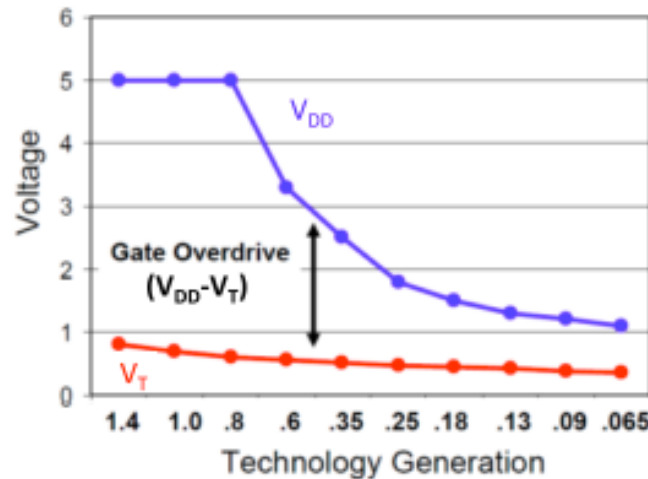
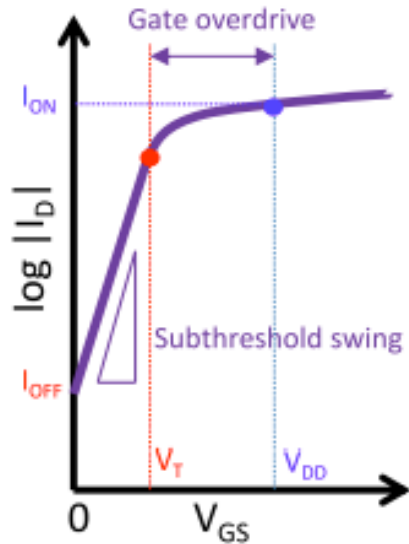
Dr. Aaron D. Franklin

Outline

- Motivation for mechanical switching
- M/NEMS basics
- M/NEMS fabrication
- NEMS (electrostatic) digital logic example
- NEMS (piezoelectric) digital logic example
- NEMS (piezoresistive) digital logic example
- NEMS circuits

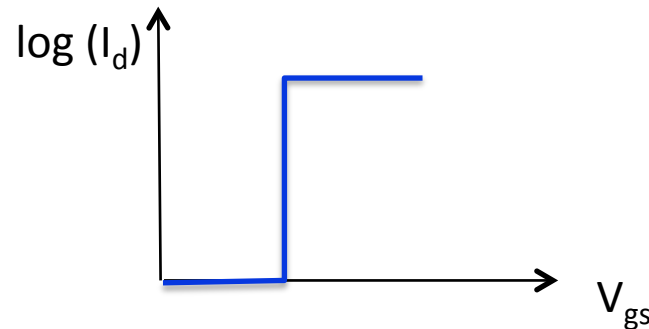
Motivation for mechanical switching

- The problem we've come to know so well:



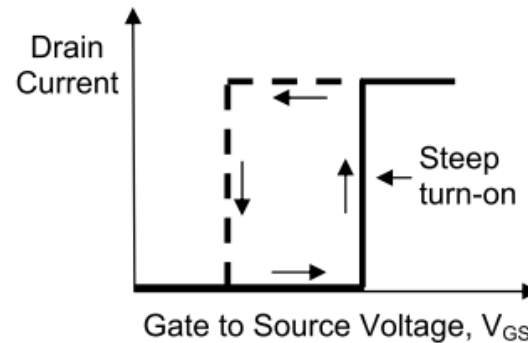
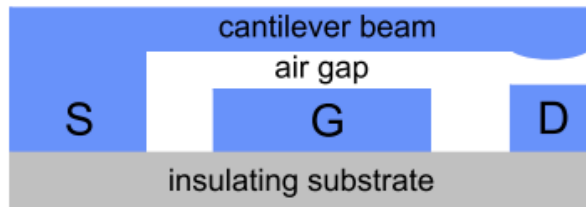
T. Liu et al., NEMS Switch Technology (Book Chapter in *Emerging Nanoelectronic Devices*), preprint (2014).

- The perfect switch:



M/NEMS (Micro/NanoElectroMechanical System) basics

- Electrical contact (current flow) achieved by mechanical manipulation of a material

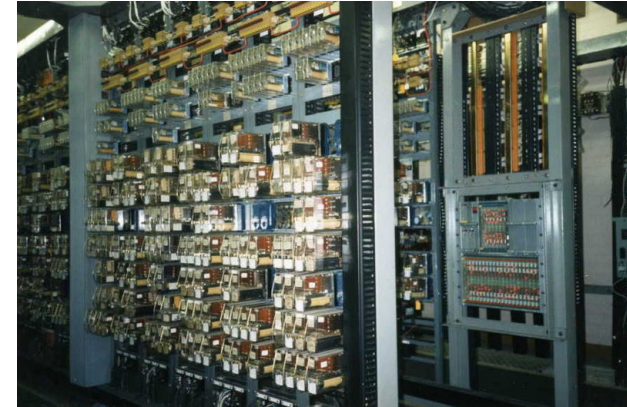
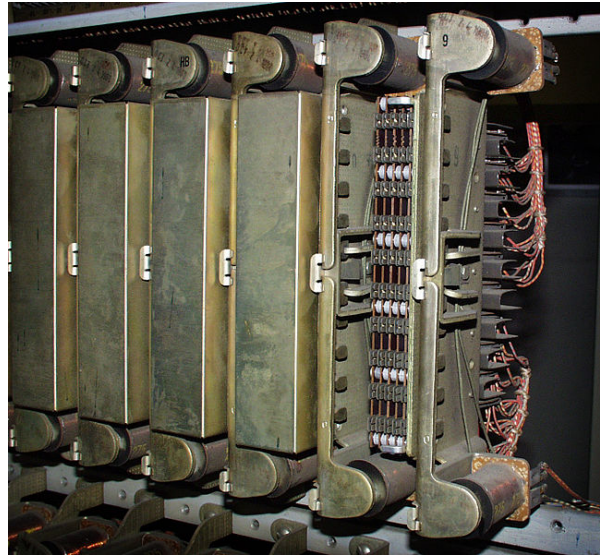
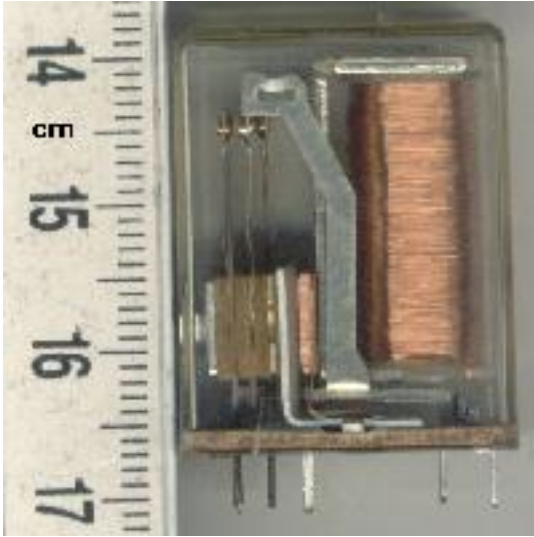


- Actuation mechanisms
 - Electromagnetic (issues: area consumption, insufficient E efficiency)
 - Electrothermal (issues: insufficient E efficiency)
 - Electrostatic (issues: challenging fabrication, limited speed)
 - Piezoelectric (issues: materials/fabrication challenging)
 - Piezoresistive (issues: uncertain scalability, challenging fabrication)

Contenders for digital computing devices

M/NEMS (Micro/NanoElectroMechanical System) basics

- NEMS, also called 'relays' because of their history

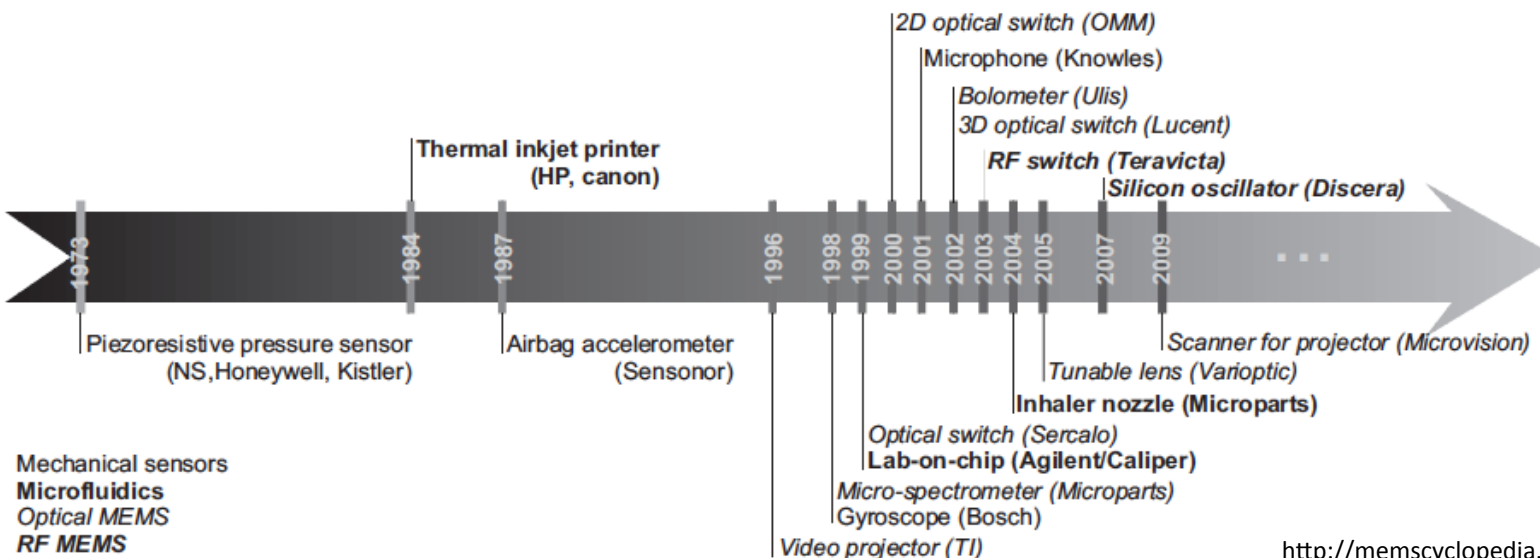


- Originally invented in ~1830's to improve the electrical telegraph
- Found use in early logic operations before being overrun by vacuum tubes
- Still major components of large machinery

M/NEMS (Micro/NanoElectroMechanical System) basics

- M/NEMS is not just about switches, but is a field with a myriad of applications/products
 - RF-MEMS
 - Accelerometers
 - Pressure/mass sensors
 - Microfluidics
 - etc.

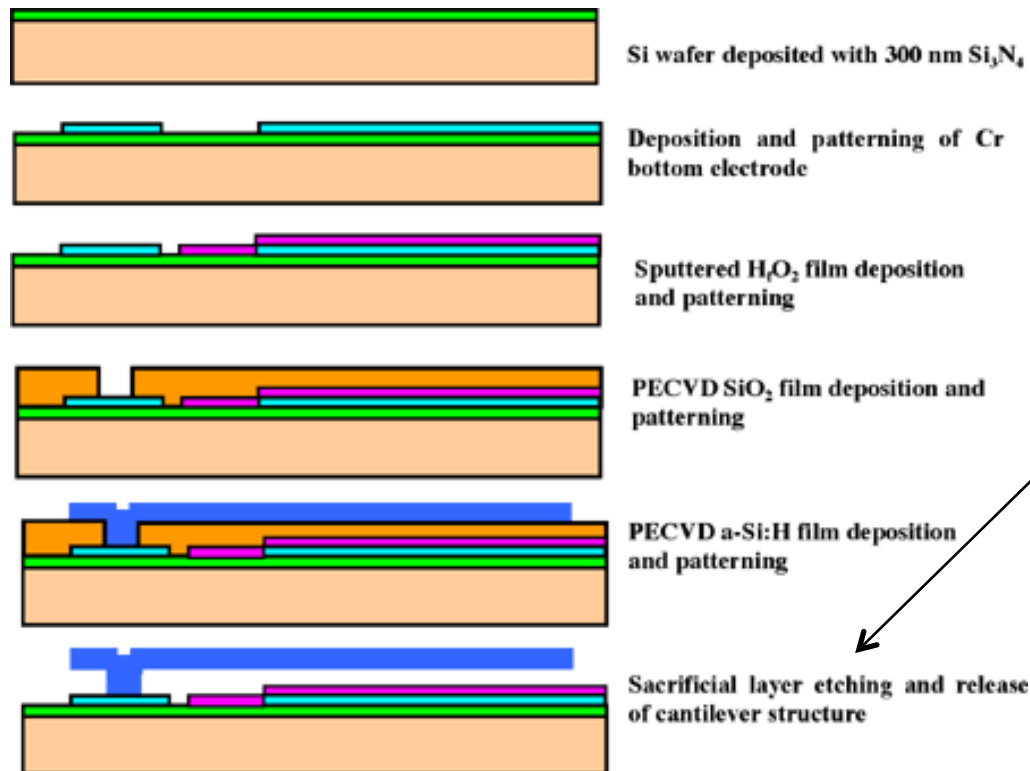
Product type	Examples
Pressure sensor	Manifold pressure (MAP), tire pressure, blood pressure..
Inertia sensor	Accelerometer, gyroscope, crash sensor...
Microfluidics / bioMEMS	Inkjet printer nozzle, micro-bio-analysis systems, DNA chips...
Optical MEMS / MOEMS	Micro-mirror array for projection (DLP), micro-grating array for projection (GLV), optical fiber switch, adaptive optics...
RF MEMS	High Q-inductor, switches, antenna, filter..
Others	Relays, microphone, data storage, toys...



<http://memscyclopedia.org/Document/introMEMS.pdf>

M/NEMS fabrication

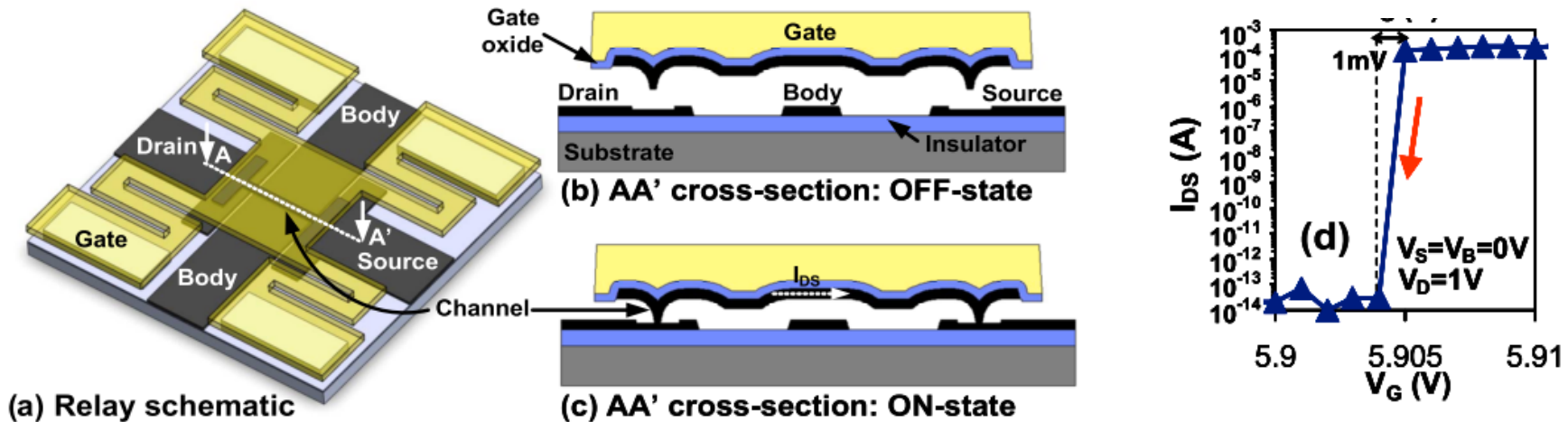
- “Micromachining” and “MEMS fabrication” are coined terms related to making M/NEMS devices
- Key step: release



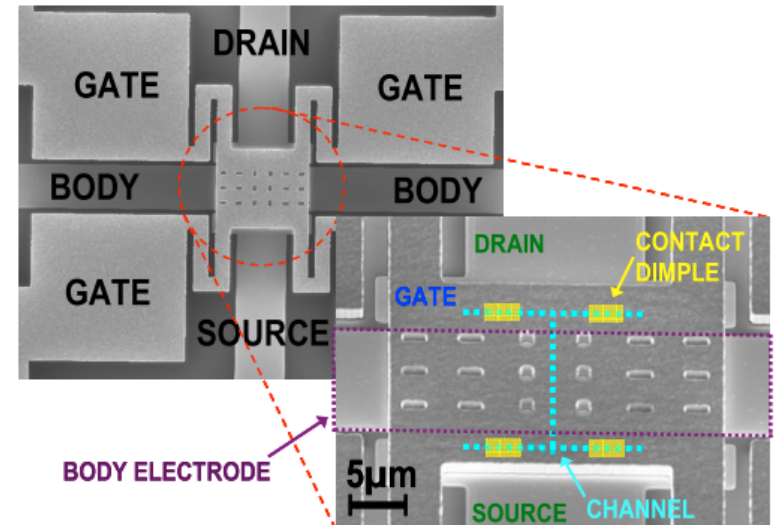
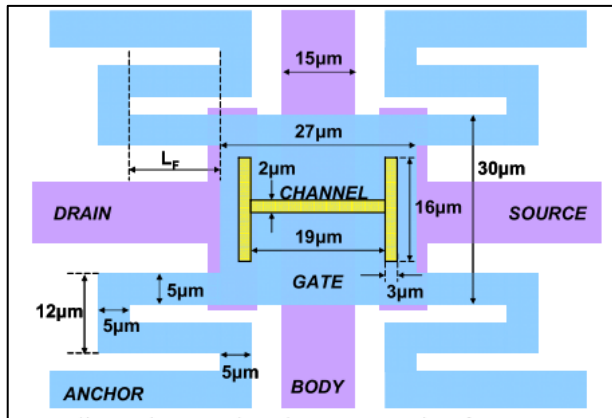
Potential collapse of cantilever, or overetch of sacrificial layer, damage to cantilever or substrate, etc.

NEMS (electrostatic) digital logic example

- 4-terminal device using a body bias to tune polarity



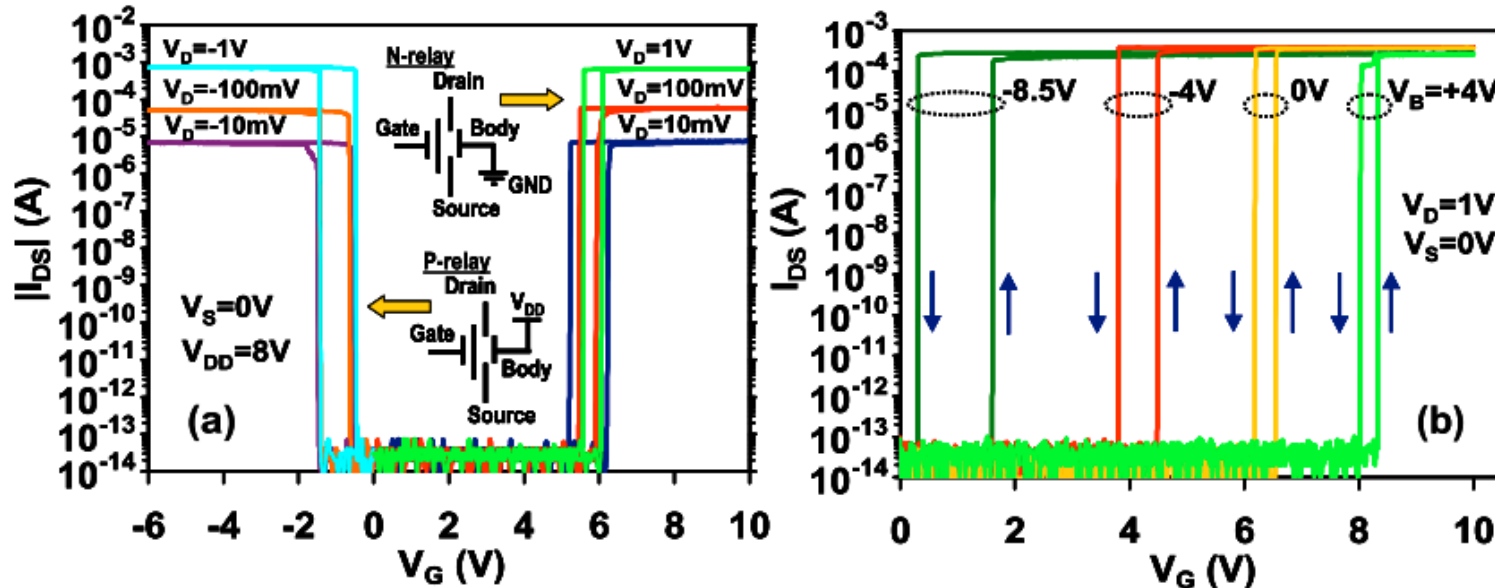
More MEMS than NEMS!



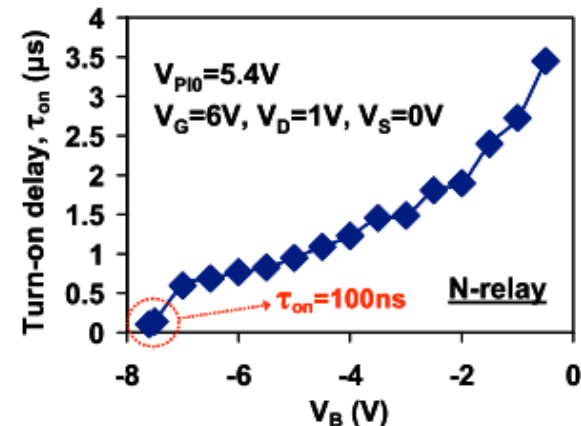
R. Nathanael et al., *IEDM Technical Digest*, pp. 9.4.1-4, 2009.

NEMS (electrostatic) digital logic example

- Mimic n- and p-type operation by adjusting body bias



- Larger the body bias, larger the hysteresis
- Surface adhesion forces causing hysteresis
- Contact resistance challenging to control
- Logic demonstrated

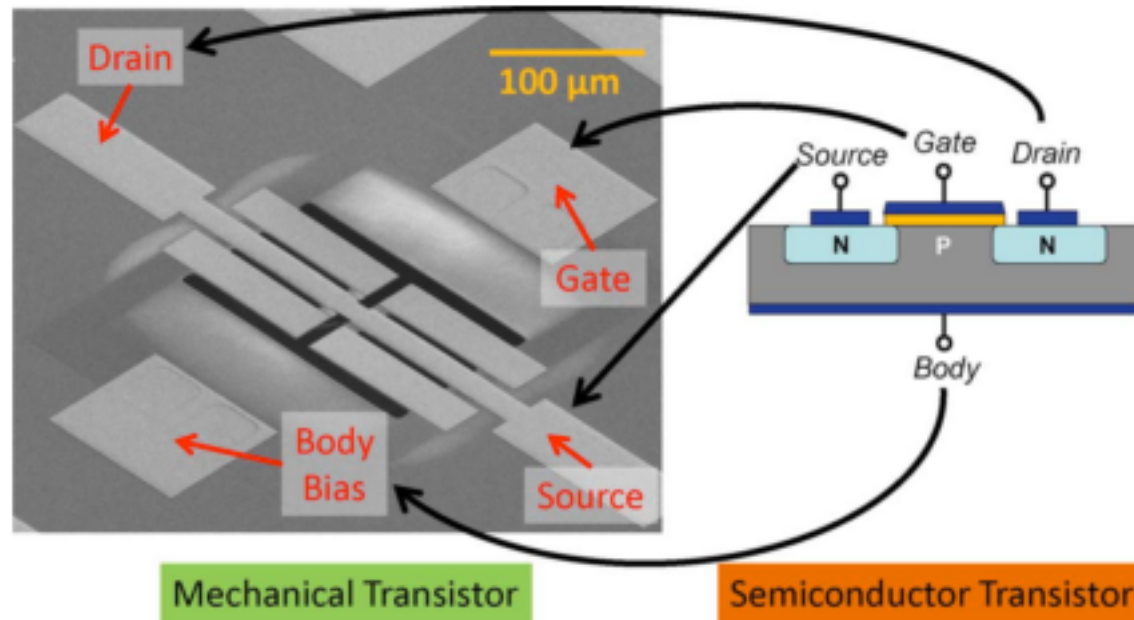


NEMS (electrostatic) digital logic example

- Advantages
 - Excellent low energy option demonstrated
 - Ability to yield complementary logic function
 - Potentially reduce needed buffers in logic to offset larger device size compared to CMOS
 - High current
- Challenges
 - Fabrication is challenging, especially to scale
 - Contact resistance effects –surface deformation, adhesion forces, uniformity, etc.
 - Slow switching speed (not RC-delay, but mechanical delay limited)
 - $\sim 100\text{s ns}$ vs. $\sim 1\text{ ps}$ for CMOS
 - Hysteresis (“pull-in operation”)
 - Reliability (how many times can you switch these things?)

NEMS (piezoelectric) digital logic example

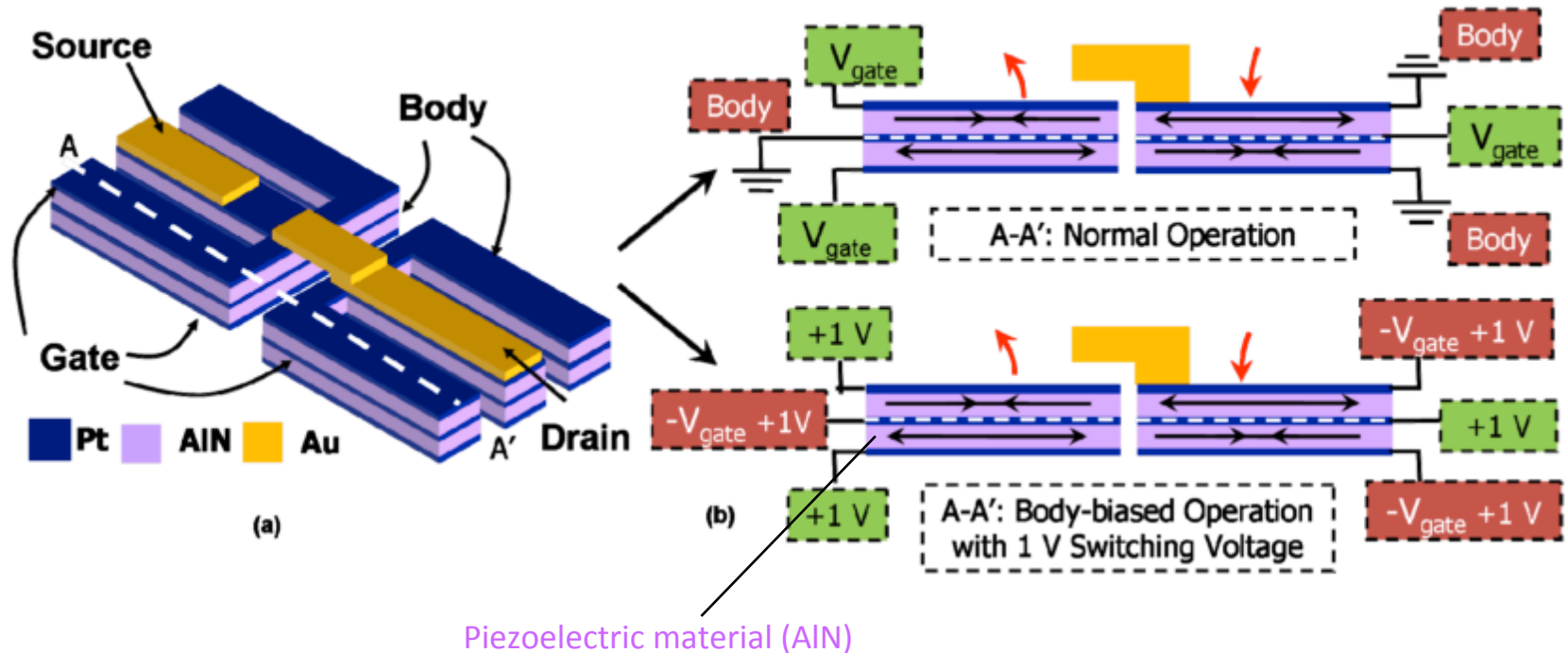
- Compare device to MOSFET:



- Effort to increase device community comfort with NEMS
- Huge difference in scale

NEMS (piezoelectric) digital logic example

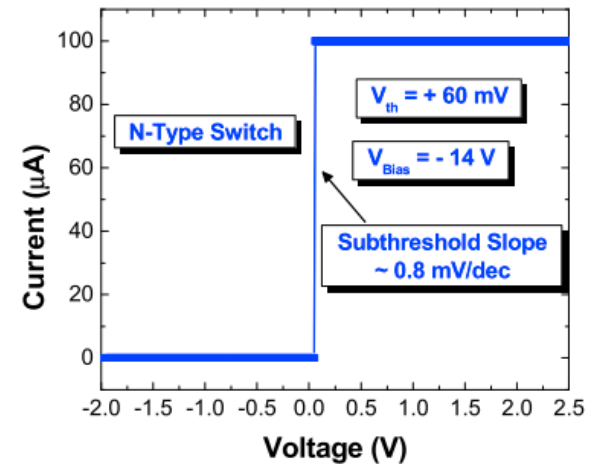
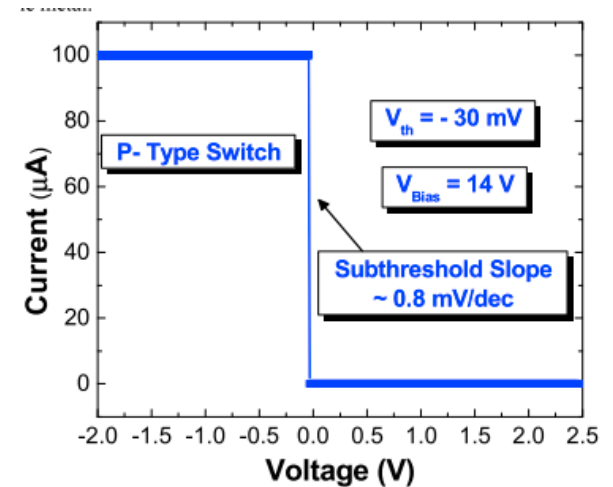
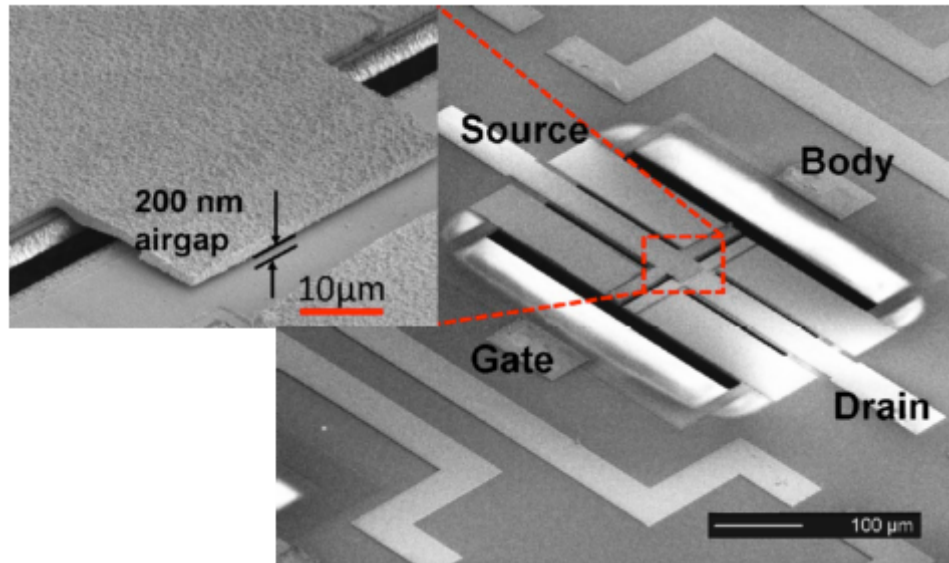
- Inverse piezoelectric effect
 - Material deformation in response to electric field



→ Applying a gate voltage creates an electric field between the gate plates and the body plates, causing the PE material between the plates to expand/retract, causing the drain cantilever to contact the source region.

NEMS (piezoelectric) digital logic example

- Compare device to MOSFET:



→ Body bias enables n- and p-type operation

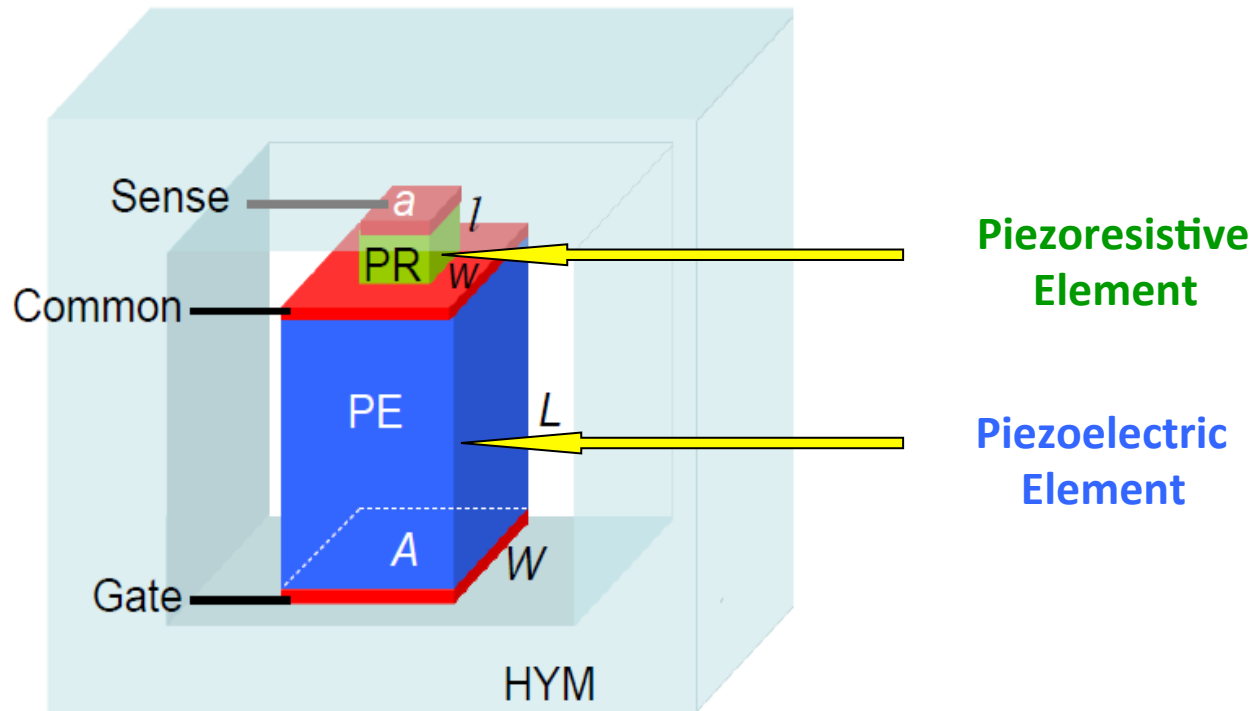
→ Switching time: $\sim 220 \text{ ns}$

NEMS (piezoelectric) digital logic example

- Advantages
 - Excellent low energy option demonstrated
 - Ability to yield complementary logic function
 - Potentially reduce needed buffers in logic to offset larger device size compared to CMOS
 - High current
 - No hysteresis
- Challenges
 - Fabrication is challenging, especially to scale
 - Contact resistance effects –surface deformation, uniformity, etc.
 - Slow switching speed (not RC-delay, but mechanical delay limited)
 - ~ 200 ns vs. ~ 1 ps for CMOS
 - Reliability (how many times can you switch these things?)

NEMS (piezoresistive) digital logic example

- IBM has a sizable effort towards a piezoelectronic transistor (PET)
 - DARPA funded with U-Wisconsin and Penn State

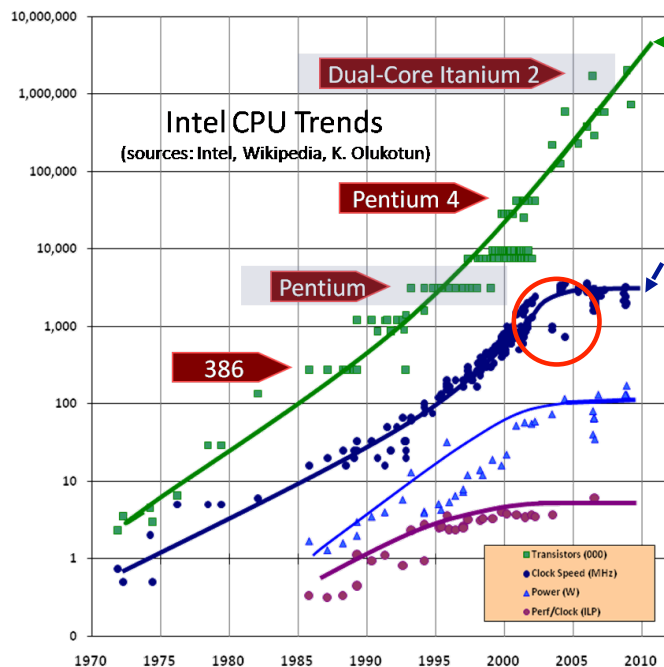


Slides courtesy of D. Newns (IBM)

NEMS (piezoresistive) digital logic example

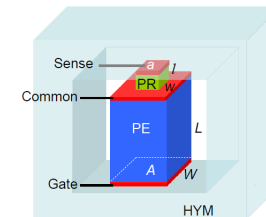
- Motivation – Overcome CMOS speed block
 - THIS LOOK FAMILIAR??? SEEN SEVERAL TIMES IN CLASS NOW AND THEY USE IT TO MOTIVATE NEMS!

Moore's Law



→ Moore's Law: transistor density is *still increasing*

- But CMOS clock speed has **not increased** since 2003– limiting processor compute power
- Line voltage V_{DD} has **stopped decreasing** so power rises unacceptably if speed increases.
- Invent a new type of fast switch with novel physics operable at **low voltage/power**
- Our PiezoElectronic Transistor (PET) is shown by simulation and theory (based on bulk material properties) to achieve this goal.

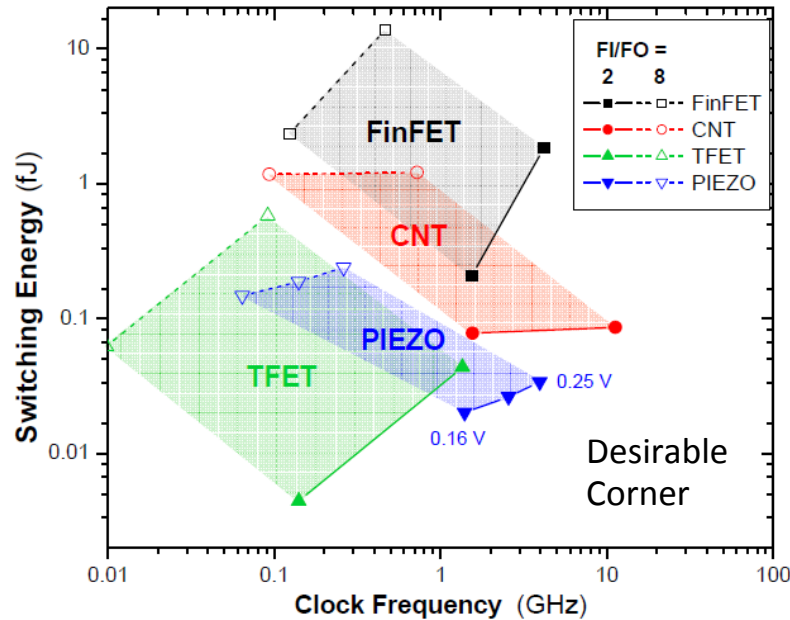


Slides courtesy of D. Newns (IBM)

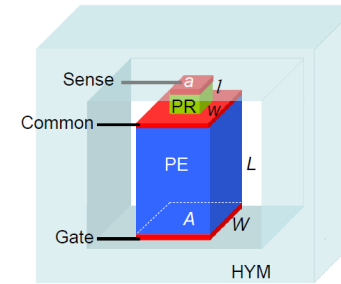
Reduce server farm, supercomputer, hand-held device power consumption.

NEMS (piezoresistive) digital logic example

- PET performance comparison



**11nm Technology study:
The PET has impressive advantages!**



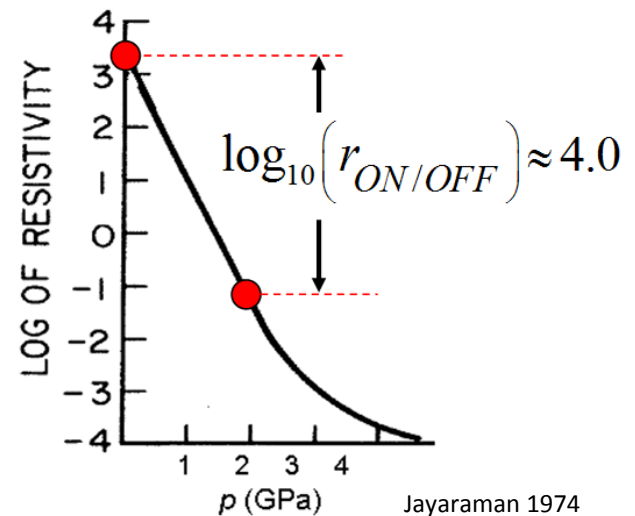
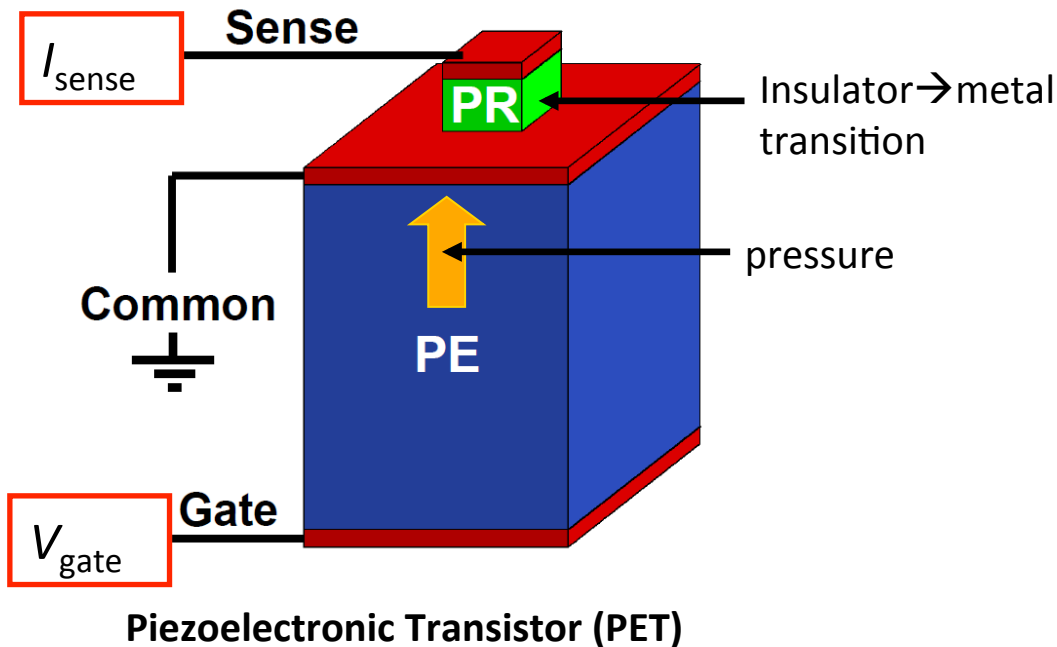
PET low power, high speed, performance compares favorably with other Switching devices. Fanout supported.

Power up to factor of 50 saved over the FinFET.

NEMS (piezoresistive) digital logic example

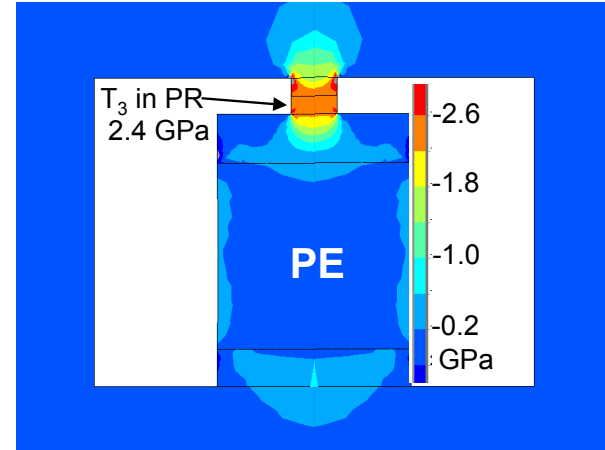
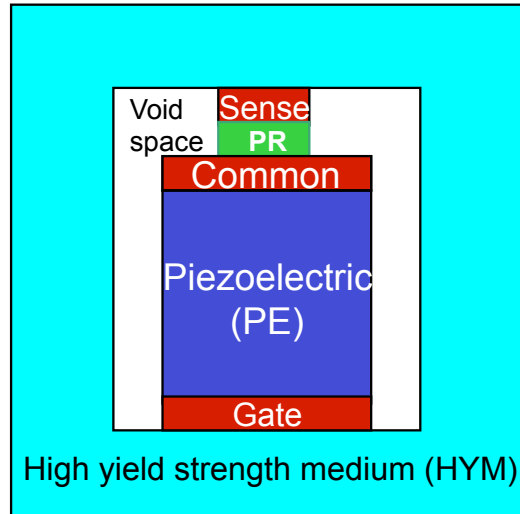
- Piezotronics – Electrical viewpoint

A **gate** voltage on a **piezoelectric** (PE) applies **pressure** to a **piezoresistive** (PR) material which induces an **insulator**→**metal** transition, turning on the current through **sense**.



NEMS (piezoresistive) digital logic example

- Piezotronics – Mechanical viewpoint



The Gate/PE/Common/PR/Sense sandwich is embedded in a **high yield strength medium (HYM)**; e.g., SiN), to hold the Sense-Drive physical distance constant.

The area ratio $\text{Area}_{\text{PR}} \ll \text{Area}_{\text{PE}}$ (a/A) steps up the pressure in the PR – the **hammer and nail principle**.

A void space allows unconstrained motion of the components.

NEMS (piezoresistive) digital logic example

- Advantages
 - Excellent low energy option demonstrated
 - Ability to yield complementary logic function
 - Potentially reduce needed buffers in logic to offset larger device size compared to CMOS
 - High current
 - No hysteresis
 - Switching speed comparable to CMOS (theoretical)
- Challenges
 - Fabrication is challenging, especially to scale
 - Material quality/uniformity effects
 - Reliability (how many times can you switch these things?)

NEMS circuits

- Most demonstrations of NEMS provides a demo of a logic function (at least inverter), often more advanced
 - V_{pi} (which is V_t) is well-defined and can thus yield logic function, even though it is very SLOW logic!

